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1. A semiconductor die package, comprising:

a flexible substrate having first and second surfaces;

a first support frame associated with at least one of said first and second surfaces for supporting said flexible substrate, said first support frame defining a cavity;

a semiconductor die containing an array of pixels positioned within said cavity, said semiconductor die supported by said flexible substrate;

a lens structure having an optical path to said array of pixels on said semiconductor die; and

a second support frame associated with the other of said first and second surfaces.

- The semiconductor die package of claim 1, wherein said second support frame defines a cavity.
- The semiconductor die package of claim 2, wherein said cavity defined by said second support frame is substantially aligned with said cavity defined by said first support frame.

- 4. The semiconductor die package of claim 2, further comprising a rigid structure positioned within said cavity defined by said second support frame
- 5. The semiconductor die package of claim 4, wherein said rigid structure includes a heat conductive element.
- 6. The semiconductor die package of claim 1, wherein said first and second support frames are coupled to each other through holes formed within said flexible substrate.
- 7. The semiconductor die package of claim 1, wherein said flexible substrate is an elastomeric substrate.
- 8. The semiconductor die package of claim 7, wherein said elastomeric substrate is selected from a group comprising epoxy, polyimide, and polyester.
- 9. The semiconductor die package of claim 8, wherein said polyimide comprises DuPont Kapton®.
- 10. The semiconductor die package of claim 7, wherein said elastomeric substrate is selected from a material capable of withstanding a 180° angle bend at a radius of at least 1/8" or less.
- 11. The semiconductor die package of claim 7, wherein said elastomeric substrate is selected from a material having a tensile strength of about 10 kpsi or greater, as measured by ASTM D-882-83 Method A.

- 12. The semiconductor die package of claim 7, wherein said elastomeric substrate is selected from a material having a tensile modulus of about 200 kpsi or greater, as measured by ASTM D-882-83 Method A.
- 13. The semiconductor die package of claim 7, wherein said elastomeric substrate is selected from a material having an elongation property of about 25% or more, as measured by ASTM D-882-83 Method A.
- 14. The semiconductor die package of claim 7, wherein said elastomeric substrate has at least one conductive line formed therein,
- 15. The semiconductor die package of claim 14, wherein said semiconductor die is electrically coupled to said at least one conductive line by wire bonds.
- 16. The semiconductor die package of claim 14, wherein said semiconductor die is electrically coupled to said at least one conductive line by conductive pads.
- 17. The semiconductor die package of claim 1, wherein at least one of said first or second surfaces of said flexible substrate has at least one conductive line formed thereon.
- 18. The semiconductor die package of claim 1, further comprising an infrared lens formed over said semiconductor die.

19. A semiconductor assembly comprising:

a semiconductor die package, said semiconductor die package comprising:

- a flexible substrate having first and second surfaces,
- a first support frame associated with at least one of said first and second surfaces for supporting said flexible substrate, said first support frame defining a cavity,
- a semiconductor die containing an array of pixels supported by said flexible substrate and positioned within said cavity,
- a lens structure providing an optical path to said array of pixels, and
- a second support frame associated with the other of said first and second surfaces of said flexible substrate; and

an edge connector electrically coupled to said semiconductor die package.

- 20. The semiconductor assembly of claim 19, wherein said second support frame of said semiconductor die package defines a cavity.
- 21. The semiconductor assembly of claim 20, wherein said cavity defined by said second support frame is substantially aligned with said cavity defined by said first support frame.

- 22. The semiconductor assembly of claim 20, wherein said semiconductor die package further comprises a rigid structure within said cavity defined by said second support frame.
- 23. The semiconductor assembly of claim 22, wherein said rigid structure includes a heat conductive element.
- 24. The semiconductor assembly of claim 19, wherein said first and second support frames of said semiconductor die package are coupled to each other through holes formed within said flexible substrate.
- 25. The semiconductor assembly of claim 19, wherein said flexible substrate of said semiconductor die package is an elastomeric substrate.
- 26. The semiconductor die package of claim 25, wherein said elastomeric substrate is selected from a group comprising epoxy, polyimide, and polyester.
- 27. The semiconductor die package of claim 25, wherein said polyimide comprises DuPont Kapton®.
- 28. The semiconductor die package of claim 25, wherein said elastomeric substrate is selected from a material capable of withstanding a 180° angle bend at a radius of at least 1/8" or less.
- 29. The semiconductor die package of claim 25, wherein said elastomeric substrate is selected from a material having a tensile strength of about 10 kpsi or greater, as measured by ASTM D-882-83 Method A.

- 30. The semiconductor die package of claim 25, wherein said elastomeric substrate is selected from a material having a tensile modulus of about 200 kpsi or greater, as measured by ASTM D-882-83 Method A.
- 31. The semiconductor die package of claim 25, wherein said elastomeric substrate is selected from a material having an elongation property of about 25% or more, as measured by ASTM D-882-83 Method A.
- 32. The semiconductor assembly of claim 25, wherein said elastomeric substrate has at least one conductive line formed therein.
- 33. The semiconductor assembly of claim 19, wherein said semiconductor die package further comprises a conductive line formed on at least one of said first and second surfaces of said flexible substrate.
- 34. The semiconductor assembly of claim 19, wherein said semiconductor die package further comprises an infrared lens formed over said semiconductor die.
 - 35. An imaging apparatus comprising:

a processor; and

an image sensing unit having a semiconductor die package and an edge connector electrically coupling said processor and said semiconductor die package, said semiconductor die package comprising:

a flexible substrate having first and second surfaces,

a first support frame associated with at least one of said first and second surfaces for supporting said flexible substrate, said first support frame defining a cavity,

a semiconductor die containing an array of pixels supported by said flexible substrate and positioned within said cavity;

a lens structure providing an optical path to said array of pixels, and

a second support frame associated with the other of said first and second surfaces of said flexible substrate.

- 36. The imaging apparatus of claim 35, wherein said semiconductor die package further comprises a cavity defined by said second support frame.
- 37. The imaging apparatus of claim 36, wherein said cavity defined by said second support frame is substantially aligned with said cavity defined by said first support frame.
- 38. The imaging apparatus of claim 36, wherein said semiconductor die package further comprises a rigid structure within said cavity of said second support frame.
- 39. The imaging apparatus of claim 38, wherein said rigid structure includes a heat conductive element.

- 40. The imaging apparatus of claim 35, wherein said first and second support frames of said semiconductor die package are coupled to each other through holes formed within said flexible substrate.
- 41. The imaging apparatus of claim 35, wherein said flexible substrate of said semiconductor die package is an elastomeric substrate. CLAIMS 42-58 (CANCELLED)